



# 40/9 w/ Election  
PATENT  
740756-1638  
3/27/01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT application of:

Hisashi OHTANI et al.

Application No.: 08/807,737

Filed: February 27, 1997

For: METHOD FOR MANUFACTURING  
SEMICONDUCTOR DEVICE

) Art Unit: 2813

) Examiner: E. Pert

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231, on March 19, 2001

Guttmann J. Cantrell

**AMENDMENT AND RESPONSE**  
**TO RESTRICTION/ELECTION**  
**OF SPECIES REQUIREMENT**

Commissioner of Patents  
Washington, D.C. 20231

March 19, 2001

Dear Sir:

In response to the Restriction and Election of Species Requirement mailed December 19, 2000, the period for responding having been extended two (2) months, Applicants hereby elect Species III, Claims 60-62, 72-74, 81, and 83, drawn to a method of disposing a catalyst metal on a silicon dioxide "wetting layer" to improve crystallization.

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01 FC:103 18.00 OP  
02 FC:102 80.00 OP

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